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Nuclear Instruments and Methods in Physics Research B 121 (1997) 525–534

NIM B
Beam Interactions with Materials & Atoms

Author index

Aizawa, T., see Hishita, S. . . . 121 (1997) 157
Aizawa, T., see Oyoshi, K. . . . 121 (1997) 184
Akizuki, M., J. Matsuo, I. Shin, M. Harada, S. Ogasawara, A. Doi and I. Yamada, Irradiation effects of O_2 cluster ions for lead oxide film formation . . . 121 (1997) 166
Akizuki, M., see Matsuo, J. . . . 121 (1997) 459
Ando, M., see Yamamoto, A. . . . 121 (1997) 275
Ando, Y., see Yokota, K. . . . 121 (1997) 295
Aoki, T., J. Matsuo, Z. Insepov and I. Yamada, Molecular dynamics simulation of damage formation by cluster ion impact . . . 121 (1997) 49
Aoki, T., see Seki, T. . . . 121 (1997) 498
Aoki, Y., see Mitamura, T. . . . 121 (1997) 271
Arashi, K., see Mitamura, T. . . . 121 (1997) 271
Ashimura, Y., see Iida, S. . . . 121 (1997) 162
Auyeung, R.C.Y., see Horwitz, J.S. . . . 121 (1997) 371

Baba, A., D. Bai, T. Sadoh, A. Kenjo, H. Nakashima, H. Mori and T. Tsurushima, Behavior of radiation-induced defects and amorphization in silicon crystal . . . 121 (1997) 299
Baba, K. and R. Hatada, Preparation of amorphous carbon thin films by ion beam assisted ECR-plasma CVD . . . 121 (1997) 129
Baba, K., see Suda, Y. . . . 121 (1997) 396
Badaye, M., see Pindoria, G. . . . 121 (1997) 141
Bader, S.D., see Rüders, F. . . . 121 (1997) 30
Bai, D., see Baba, A. . . . 121 (1997) 299
Baldo, P.M., see Rüders, F. . . . 121 (1997) 30
Boyd, I.W. and J.Y. Zhang, New large area ultraviolet lamp sources and their applications . . . 121 (1997) 349
Bulatov, V., M. Nastar, J. Justo and S. Yip, Atomistic modeling of crystal-defect mobility and interactions . . . 121 (1997) 251
Byun, D.H., see Chang, G.S. . . . 121 (1997) 244

Caulfield, J., see Horwitz, J.S. . . . 121 (1997) 371
Chan, C., see Husein, I.F. . . . 121 (1997) 226
Chang, G.S., S.M. Jung, J.H. Song, H.B. Kim, J.J. Woo, D.H. Byun and C.N. Whang, Cohesive energy effects on the atomic transport induced by ion beam mixing . . . 121 (1997) 244
Chayahara, A., see Enders, B. . . . 121 (1997) 73
Chayahara, A., see Nagasaka, H. . . . 121 (1997) 279
Chayahara, A., see Ikeyama, M. . . . 121 (1997) 335
Chen, L.J., see Yang, J.J. . . . 121 (1997) 195
Chen, L.J., S.L. Cheng and B.Y. Tsui, Metal contacts on shallow junctions . . . 121 (1997) 231
Chen, L.J., see Yang, J.J. . . . 121 (1997) 291
Cheng, S.L., see Chen, L.J. . . . 121 (1997) 231
Cheung, N.W., see Jones, E.C. . . . 121 (1997) 216
Cho, H.J., I.G. Yu and C.K. Hwangbo, Inhomogeneous optical SiO_xN_y thin films prepared by ion assisted deposition . 121 (1997) 137
Cho, M.H., see Choi, S.C. . . . 121 (1997) 170
Choi, B.H., see Han, J.G. . . . 121 (1997) 79
Choi, S.C., M.H. Cho, S.W. Whangbo, C.N. Whang, C.E. Hong, N.Y. Kim, J.S. Jeon, S.I. Lee and M.Y. Lee, Heteroepitaxial growth of Y_2O_3 films on Si(100) by reactive ionized cluster beam deposition . . . 121 (1997) 170
Chrisey, D.B., see Horwitz, J.S. . . . 121 (1997) 371
Chung, T.R., L. Yang, N. Hosoda and T. Suga, Room temperature GaAs–Si and InP–Si wafer direct bonding by the surface activated bonding method . . . 121 (1997) 203
Clerc, C., see Nakagawa, S.T. . . . 121 (1997) 36
Clissold, R.A., see Ikeyama, M. . . . 121 (1997) 335
Coffa, S., see Rimini, E. . . . 121 (1997) 18
Current, M.I., N. Ohno and T. Hara, Shallow junction formation in Si-devices: Damage accumulation and the role of photo-acoustic probes and multi-species implantation . . . 121 (1997) 262

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Danson, N., see Howson, R.P. 121 (1997) 90
Danson, N., see Howson, R.P. 121 (1997) 96
Doi, A., see Akizuki, M. 121 (1997) 166
Dorsey, P.C., see Horwitz, J.S. 121 (1997) 371

Ebe, A., E. Takahashi, N. Kuratani, S. Nishiyama, O. Imai, K. Ogata, Y. Setsuhara and S. Miyake, Interface structure between polyimide film substrate and copper film prepared by ion beam and vapor deposition (IVD) method . . . 121 (1997) 207
Ebihara, K., see Suda, Y. 121 (1997) 396
Enders, B., Y. Horino, N. Tsubouchi, A. Chayahara, A. Kinomura and K. Fujii, Carbon nitride thin films formed by low energy ion beam deposition with positive and negative ions 121 (1997) 73
Eryu, O., T. Kume, K. Nakashima, T. Nakata and M. Inoue, Formation of an ohmic electrode in SiC using a pulsed laser irradiation method 121 (1997) 419

Fan, X., M. Terasawa, T. Mitamura, T. Kohara, K. Ueda, H. Tsubakino, A. Yamamoto, T. Murakami and S. Matsumoto, Irradiation effects on the magnetic properties of $La_{1.85}Sr_{0.15}CuO_4$ by high-energy heavy ions 121 (1997) 331
Fang, X.H., see Kotani, M. 121 (1997) 302
Fitz-Gerald, J.M., see Singh, R.K. 121 (1997) 363
Franzò, G., see Rimini, E. 121 (1997) 18
Fuchigami, H., Y. Nakao, S. Tanimura, Y. Uehara, T. Kurata, S. Tsunoda, H. Niino and A. Yabe, Bis(ethynyl-styryl)benzene films grown by molecular beam deposition in a photon field 121 (1997) 422
Fujii, K., see Enders, B. 121 (1997) 73
Fujii, K., see Nagasaka, H. 121 (1997) 279
Fujioka, Y., see Kajiyama, K. 121 (1997) 315
Fujita, M., see Harada, T. 121 (1997) 383
Fujiwara, H., see Mameno, K. 121 (1997) 311
Fukatsu, K., Introduction to the Applied Laser Engineering Center (ALEC) 121 (1997) 7
Fukushima, K., see Takeuchi, D. 121 (1997) 493
Fukushima, K., see Takaoka, G.H. 121 (1997) 503
Fullerton, E.E., see Rüders, F. 121 (1997) 30

Galvagno, G., see Rimini, E. 121 (1997) 18
Gamo, K., Recent advances of focused ion beam technology 121 (1997) 464
Garrido, F., see Thomé, L. 121 (1997) 237
Gaze, J., T. Obata, N. Oyanagi, H. Izawa, W. Zhou, M. Kusunoki and Y. Ikuhara, The synthesis of diamond particles by a filament assisted CO_2 laser induced CVD 121 (1997) 427
Goppelt-Langer, P., see Mitamura, T. 121 (1997) 271
Greene, J.E. and N.-E. Lee, Si(001) epitaxy from hyperthermal beams: Crystal growth, doping, and electronic properties 121 (1997) 58
Greer, J.A., M.D. Tabat and C. Lu, Future trends for large-area pulsed laser deposition 121 (1997) 357
Guseva, M.I., see Han, J.G. 121 (1997) 79

Hall, G.W., see Howson, R.P. 121 (1997) 90
Hall, G.W., see Howson, R.P. 121 (1997) 96
Hamano, T., see Takaoka, G.H. 121 (1997) 503
Han, J.G., B.H. Choi, W. Kim and M.I. Guseva, Tribological hard layer synthesis by duplex ion beam treatment . . . 121 (1997) 79
Han, J.G., see Lee, J.W. 121 (1997) 474
Hanabusa, M., Z. Liu, N. Nakamura and H. Hasegawa, Pulsed laser deposition of silicon films for solar cell applications 121 (1997) 367
Haneda, H., see Oyoshi, K. 121 (1997) 184
Hara, T., see Current, M.I. 121 (1997) 262
Harada, M., see Akizuki, M. 121 (1997) 166
Harada, T., M. Fujita and T. Kuji, Laser annealing of an amorphous Nd–Fe–B alloy 121 (1997) 383
Hasegawa, H., see Hanabusa, M. 121 (1997) 367
Hasegawa, M., see Katsumata, H. 121 (1997) 146
Hasegawa, M., see Kobayashi, N. 121 (1997) 199
Hatada, R., see Baba, K. 121 (1997) 129
Hayashi, N., see Katsumata, H. 121 (1997) 146
Hayashi, N., see Kobayashi, N. 121 (1997) 199
Haynes, T.E., Y. Shigesato, I. Yasui, N. Taga and H. Odaka, Ion beam modification of transparent conducting indium-tin-oxide thin films 121 (1997) 221
Hirai, K., see Yokota, K. 121 (1997) 295

Hirata, K., Y. Kobayashi, S. Hishita, X. Zhao, Y. Itoh, T. Ohdaira, R. Suzuki and Y. Ujihira, Variable-energy positron beam system and its application to depth-selective defect analysis 121 (1997) 267
Hishita, S., K. Oyoshi, S. Suehara and T. Aizawa, Effect of oxygen adsorption on ion beam induced recrystallization of copper films 121 (1997) 157
Hishita, S., see Oyoshi, K. 121 (1997) 184
Hishita, S., see Hirata, K. 121 (1997) 267
Honda, S., see Kiyohara, S. 121 (1997) 191
Honda, S., see Taniguchi, J. 121 (1997) 507
Honda, S., see Kiyohara, S. 121 (1997) 510
Hong, C.E., see Choi, S.C. 121 (1997) 170
Horino, Y., see Enders, B. 121 (1997) 73
Horwitz, J.S., D.B. Chrisey, P.C. Dorsey, L.A. Knauss, J.M. Pond, M. Wilson, M.S. Osofsky, S.B. Qadri, J. Caulfield and R.C.Y. Auyeung, Pulsed laser deposition of electronic ceramics 121 (1997) 371
Hosoda, N., see Chung, T.R. 121 (1997) 203
Hosoda, N., see Yang, L. 121 (1997) 519
Hosokawa, K., see Yokota, K. 121 (1997) 295
Howson, R.P., Synthesis of sputtered thin films in low energy ion beams 121 (1997) 65
Howson, R.P., I. Safi, G.W. Hall and N. Danson, Sputtering of indium-tin oxide 121 (1997) 96
Howson, R.P., N. Danson and G.W. Hall, Reactive magnetron sputtering of silicon to produce silicon oxide 121 (1997) 90
Husein, I.F., S. Qin, Y.-Z. Zhou and C. Chan, Plasma immersion ion implantation for materials modification and semiconductor processing: Carbon nitride films and poly-Si TFTs hydrogenation 121 (1997) 226
Hwangbo, C.K., see Cho, H.J. 121 (1997) 137

Iida, S., T. Shindo, S. Matsuura and Y. Ashimura, Effects of accelerated ion beam deposition to form thin metal films on silicon 121 (1997) 162
Iida, T., see Kotani, M. 121 (1997) 302
Ikegami, Y., see Nakai, H. 121 (1997) 125
Ikeyama, M., T. Tanaka, A. Chayahara, R.A. Clissold, L.S. Wielunski and M.V. Swain, Ultramicrohardness measurement of ion implanted alumina 121 (1997) 335
Ikeyama, M., see Miyagawa, Y. 121 (1997) 340
Ikuhara, Y., see Gaze, J. 121 (1997) 427
Imai, M., see Ogura, M. 121 (1997) 470
Imai, O., see Ebe, A. 121 (1997) 207
Imai, O., see Murakami, Y. 121 (1997) 212
Imanishi, N., see Ogura, M. 121 (1997) 470
Inoue, M., Y. Suzuki and T. Takagi, Review of Ion Engineering Center and related projects in Ion Engineering Research Institute 121 (1997) 1
Inoue, M., see Ohtani, S. 121 (1997) 319
Inoue, M., see Eryu, O. 121 (1997) 419
Insepov, Z. and I. Yamada, Computer simulation of crystal surface modification by accelerated cluster ion impacts . . 121 (1997) 44
Insepov, Z., see Aoki, T. 121 (1997) 49
Insepov, Z., see Seki, T. 121 (1997) 498
Inuishi, M., see Murakami, T. 121 (1997) 257
Irie, M., H. Ohara, A. Nakayama, N. Kitagawa and T. Nomura, Deposition of Ni–TiN nano-composite films by cathodic arc ion-plating 121 (1997) 133
Ishikawa, T., H. Kawakami and H. Mori, Laser purification of metals (I); high Rydberg states of Ni, Ag, and Pd . . . 121 (1997) 437
Ishikawa, T., see Mori, H. 121 (1997) 442
Itadani, T. and K. Saito, Controlling the molecular orientation of liquid crystalline polymer films deposited by polarized-laser chemical vapor deposition 121 (1997) 415
Itoh, A., see Ogura, M. 121 (1997) 470
Itoh, Y., see Minato, M. 121 (1997) 187
Itoh, Y., see Hirata, K. 121 (1997) 267
Itsuki, A., H. Uchida, M. Satou and K. Ogi, Properties of a new organo silver compound for MOCVD 121 (1997) 116
Iwase, M., see Nozaki, S. 121 (1997) 455
Izawa, H., see Gaze, J. 121 (1997) 427

Jeon, J.S., see Choi, S.C. 121 (1997) 170
Jiang, D.S., see Kotani, M. 121 (1997) 302
Jiang, L., see Moro, L. 121 (1997) 151
Jones, E.C. and N.W. Cheung, Plasma doping optimization for ultra-shallow junctions 121 (1997) 216

Jung, S.M., see Chang, G.S. 121 (1997) 244
Justo, J., see Bulatov, V. 121 (1997) 251

Kajiyama, K., T. Yoneda, Y. Fujioka and Y. Kido, Si–O bond formation by oxygen implantation into silicon 121 (1997) 315
Kajiyama, K., see Kawashita, M. 121 (1997) 323
Kakemoto, H., see Kobayashi, N. 121 (1997) 199
Kakishita, K., S. Kondo and T. Suda, Photoresponse of zinc phosphide thin films grown by ionized cluster beam deposition 121 (1997) 175
Kamijo, E., T. Nakamura and Y. Tani, AFM observations of DLC films prepared by the ECR sputtering method . . . 121 (1997) 110
Kaneko, T., see Seki, T. 121 (1997) 498
Kang, H.J., M.W. Lee, J.H. Kim and C.N. Whang, Molecular dynamics simulation for ionized cluster beam deposition 121 (1997) 53
Katsumata, H., N. Kobayashi, Y. Makita, M. Hasegawa, N. Hayashi, H. Shibata and S. Uekusa, Photoluminescence studies of epitaxial $Si_{1-x}Ge_x$ and $Si_{1-x-y}Ge_xC_y$ layers on Si formed by ion beam synthesis 121 (1997) 146
Katsumata, H., see Kobayashi, N. 121 (1997) 199
Kawabata, T., see Tahara, H. 121 (1997) 446
Kawakami, H., see Ishikawa, T. 121 (1997) 437
Kawakami, H., see Mori, H. 121 (1997) 442
Kawasaki, Y., see Murakami, T. 121 (1997) 257
Kawashita, M., F. Miyaji, T. Kokubo, G.H. Takaoka, I. Yamada, Y. Suzuki and K. Kajiyama, Preparation of glass for radiotherapy of cancer by P^+ ion implantation at 100 keV 121 (1997) 323
Kawasumi, Y., see Kotani, M. 121 (1997) 302
Kenjo, A., see Baba, A. 121 (1997) 299
Kido, Y., see Nakata, J. 121 (1997) 306
Kido, Y., see Kajiyama, K. 121 (1997) 315
Kim, C.Y., see Lee, J.W. 121 (1997) 474
Kim, H.B., see Chang, G.S. 121 (1997) 244
Kim, H.K., see Kim, S.-H. 121 (1997) 514
Kim, J.H., see Kang, H.J. 121 (1997) 53
Kim, N.Y., see Choi, S.C. 121 (1997) 170
Kim, S.-H., D.W. Moon and H.K. Kim, The behavior of fcc Cu nanocrystallites in Si(100) 121 (1997) 514
Kim, S.H., see Lee, J.W. 121 (1997) 474
Kim, T.H., see Lee, J.W. 121 (1997) 474
Kim, W., see Han, J.G. 121 (1997) 79
Kimura, S., see Kotani, M. 121 (1997) 302
Kinomura, A., see Enders, B. 121 (1997) 73
Kitagawa, N., see Irie, M. 121 (1997) 133
Kitagawa, N., see Oda, K. 121 (1997) 283
Kitani, H., N. Toyoda, J. Matsuo and I. Yamada, Incident angle dependence of the sputtering effect of Ar-cluster-ion bombardment 121 (1997) 489
Kitani, H., see Toyoda, N. 121 (1997) 484
Kitazawa, K., see Kiyohara, S. 121 (1997) 510
Kiuchi, M., T. Takeuchi and M. Yamamoto, The charge effects in the low-energy ion depositing processes 121 (1997) 154
Kiyohara, S., I. Miyamoto, K. Kitazawa and S. Honda, Ion beam assisted chemical etching of single crystal diamond chips 121 (1997) 510
Kiyohara, S., I. Miyamoto, T. Masaki and S. Honda, Ion beam smoothing of CVD diamond thin films by etchback method 121 (1997) 191
Knauss, L.A., see Horwitz, J.S. 121 (1997) 371
Kobayashi, N., D.H. Zhu, H. Katsumata, H. Kakemoto, M. Hasegawa, N. Hayashi, H. Shibata, Y. Makita, S. Uekusa and T. Tsukamoto, Crystallization of SiSn and SiSnC layers in Si by solid phase epitaxy and ion-beam-induced epitaxy 121 (1997) 199
Kobayashi, N., see Katsumata, H. 121 (1997) 146
Kobayashi, T., see Morita, E. 121 (1997) 412
Kobayashi, Y., see Hirata, K. 121 (1997) 267
Koga, Y., see Kokai, F. 121 (1997) 387
Koga, Y., see Saito, K. 121 (1997) 400
Kohara, T., see Fan, X. 121 (1997) 331
Kohtoku, Y., see Yamada, T. 121 (1997) 378
Kokai, F. and Y. Koga, Time-of-flight mass spectrometric studies on the plume dynamics of laser ablation of graphite 121 (1997) 387
Kokubo, T., see Kawashita, M. 121 (1997) 323
Kondo, S., see Kakishita, K. 121 (1997) 175

Kotani, M., T. Iida, Y. Makita, Y. Kawasumi, X.H. Fang, S. Kimura, D.S. Jiang, H. Shibata, T. Shima, T. Tsukamoto and N. Koura, Photoluminescence characterization of dually Cd^+ and N^+ ion-implanted GaAs 121 (1997) 302
Koura, N., see Kotani, M. 121 (1997) 302
Kuba, K., see Sugihara, T. 121 (1997) 392
Kuji, T., see Harada, T. 121 (1997) 383
Kumagai, M., see Yokota, K. 121 (1997) 295
Kume, T., see Eryu, O. 121 (1997) 419
Kurata, T., see Fuchigami, H. 121 (1997) 422
Kuratani, N., see Ebe, A. 121 (1997) 207
Kuratani, N., see Murakami, Y. 121 (1997) 212
Kuroi, T., see Murakami, T. 121 (1997) 257
Kusunoki, M., see Gaze, J. 121 (1997) 427

La Ferla, A., see Rimini, E. 121 (1997) 18
Lee, J.S., see Lee, J.W. 121 (1997) 474
Lee, J.W., T.H. Kim, S.H. Kim, C.Y. Kim, Y.H. Yoon, J.S. Lee and J.G. Han, Investigation of ion bombarded polymer surfaces using SIMS, XPS and AFM 121 (1997) 474
Lee, M.W., see Kang, H.J. 121 (1997) 53
Lee, M.Y., see Choi, S.C. 121 (1997) 170
Lee, N.-E., see Greene, J.E. 121 (1997) 58
Lee, S.I., see Choi, S.C. 121 (1997) 170
Liu, L., see Mitamura, T. 121 (1997) 271
Liu, Z., see Hanabusa, M. 121 (1997) 367
Lorents, D.C., see Moro, L. 121 (1997) 151
Lu, C., see Greer, J.A. 121 (1997) 357

Makita, Y., see Katsumata, H. 121 (1997) 146
Makita, Y., see Kobayashi, N. 121 (1997) 199
Makita, Y., see Kotani, M. 121 (1997) 302
Malhotra, R., see Moro, L. 121 (1997) 151
Mameno, K., H. Nagasawa, A. Nishida and H. Fujiwara, Evaluation of the gate oxide transformed by ion implantation 121 (1997) 311
Masaki, T., see Kiyohara, S. 121 (1997) 191
Matsuda, K., see Yokota, K. 121 (1997) 295
Matsui, Y., see Murakami, T. 121 (1997) 257
Matsumoto, S., see Fan, X. 121 (1997) 331
Matsuo, J., N. Toyoda, M. Akizuki and I. Yamada, Sputtering of elemental metals by Ar cluster ions 121 (1997) 459
Matsuo, J., see Aoki, T. 121 (1997) 49
Matsuo, J., see Akizuki, M. 121 (1997) 166
Matsuo, J., see Takeuchi, D. 121 (1997) 345
Matsuo, J., see Tanomura, M. 121 (1997) 480
Matsuo, J., see Toyoda, N. 121 (1997) 484
Matsuo, J., see Kitani, H. 121 (1997) 489
Matsuo, J., see Takeuchi, D. 121 (1997) 493
Matsuo, J., see Seki, T. 121 (1997) 498
Matsuo, J., see Takaoka, G.H. 121 (1997) 503
Matsuura, S., see Iida, S. 121 (1997) 162
Minato, M. and Y. Itoh, Vacuum characteristics of TiN film coated on the interior surface of a vacuum duct 121 (1997) 187
Mitamura, T., M. Terasawa, K. Arashi, L. Liu, S. Yamamoto, P. Goppelt-Langer, H. Takeshita, Y. Aoki and H. Naramoto, ERDA analysis of the depth distribution of deuterium in ion-irradiated nickel 121 (1997) 271
Mitamura, T., see Yamamoto, A. 121 (1997) 275
Mitamura, T., see Fan, X. 121 (1997) 331
Miyagawa, S., see Saitoh, K. 121 (1997) 84
Miyagawa, S., see Miyagawa, Y. 121 (1997) 340
Miyagawa, Y., S. Nakao, M. Ikeyama, K. Saitoh and S. Miyagawa, High fluence implantation of nitrogen into titanium: Fluence dependence of sputtering yield, retained fluence and nitrogen depth profile 121 (1997) 340
Miyaji, F., see Kawashita, M. 121 (1997) 323
Miyake, K. and K. Ohashi, Improved ion beam deposition system with RF sputter-type ion source 121 (1997) 102
Miyake, K., see Ohashi, T. 121 (1997) 40
Miyake, S., see Ebe, A. 121 (1997) 207
Miyamoto, I., see Kiyohara, S. 121 (1997) 191
Miyamoto, I., see Taniguchi, J. 121 (1997) 507

Miyamoto, I., see Kiyohara, S. 121 (1997) 510
Miyashita, F., see Yokota, K. 121 (1997) 295
Mizuno, B., see Takase, M. 121 (1997) 288
Moon, D.W., see Kim, S.-H. 121 (1997) 514
Mori, H., see Baba, A. 121 (1997) 299
Mori, H., see Ishikawa, T. 121 (1997) 437
Mori, H., T. Ishikawa and H. Kawakami, Laser purification of metals (II); Purification of Ni and Ag 121 (1997) 442
Morisaki, H., see Nozaki, S. 121 (1997) 455
Morishita, T., see Pindoria, G. 121 (1997) 141
Morita, E., K. Yamamuro, M. Tachiki and T. Kobayashi, Advanced eclipse pulsed laser deposition method for growth of perovskite crystals and relatives 121 (1997) 412
Moro, L., A. Paul, D.C. Lorents, R. Malhotra, R.S. Ruoff and L. Jiang, Patterning silicon carbide on silicon by ion modification of C_{60} films 121 (1997) 151
Mukai, N., see Sano, Y. 121 (1997) 432
Mukai, T., Research and development of industrial science and technology promoted by NEDO 121 (1997) 10
Murakami, T., T. Kuroi, Y. Kawasaki, M. Inuishi, Y. Matsui and A. Yasuoka, Application of nitrogen implantation to ULSI 121 (1997) 257
Murakami, T., see Fan, X. 121 (1997) 331
Murakami, Y., N. Kuratani, S. Nishiyama, O. Imai and K. Ogata, Study on the effect of the interlayer on the adhesion of 400 μm thick film 121 (1997) 212

Nagasaka, H., A. Chayahara and K. Fujii, Tribological properties of titanium nitride films prepared by dynamic ion beam mixing method 121 (1997) 279
Nagasawa, H., see Mameno, K. 121 (1997) 311
Nakagawa, S.T., L. Thomé, H. Saito and C. Clerc, The 3-D profiling of B ions implanted into Si 121 (1997) 36
Nakai, H., J. Shinohara, T. Sassa and Y. Ikegami, Surface morphology and resistivity of aluminum oxide films prepared by plasma CVD combined with ion beam irradiation 121 (1997) 125
Nakamura, N., see Hanabusa, M. 121 (1997) 367
Nakamura, T., see Kamijo, E. 121 (1997) 110
Nakano, N., see Okamoto, A. 121 (1997) 179
Nakao, S., see Saitoh, K. 121 (1997) 84
Nakao, S., see Miyagawa, Y. 121 (1997) 340
Nakao, S., see Shimizu-Iwayama, T. 121 (1997) 450
Nakao, Y., see Fuchigami, H. 121 (1997) 422
Nakashima, H., see Baba, A. 121 (1997) 299
Nakashima, K., see Eryu, O. 121 (1997) 419
Nakata, J., H. Yamazaki, Y. Yamamoto and Y. Kido, In-situ ion-beam annealing of damage in GaAs during O implantation and O-site determination by $^{18}O(p,\alpha)^{15}N$ nuclear reaction 121 (1997) 306
Nakata, R., see Tanaka, K. 121 (1997) 404
Nakata, T., see Eryu, O. 121 (1997) 419
Nakayama, A., see Irie, M. 121 (1997) 133
Nakayama, A., see Oda, K. 121 (1997) 283
Nakazono, T., see Suda, Y. 121 (1997) 396
Naramoto, H., see Mitamura, T. 121 (1997) 271
Nastar, M., see Bulatov, V. 121 (1997) 251
Niino, H., see Fuchigami, H. 121 (1997) 422
Nishida, A., see Mameno, K. 121 (1997) 311
Nishigaki, K., see Ogawa, S. 121 (1997) 328
Nishiyama, S., see Ebe, A. 121 (1997) 207
Nishiyama, S., see Murakami, Y. 121 (1997) 212
Niwa, H., see Saitoh, K. 121 (1997) 84
Nomura, T., see Irie, M. 121 (1997) 133
Nomura, T., see Oda, K. 121 (1997) 283
Nonogaki, R., S. Yamada and T. Wada, Preparation of boron nitride films by multi-source plasma CVD method . . . 121 (1997) 121
Nozaki, S., S. Sato, H. Ono, H. Morisaki and M. Iwase, Germanium nanostructures deposited by the cluster-beam evaporation technique 121 (1997) 455

Obata, T., see Gaze, J. 121 (1997) 427
Obata, M., see Sano, Y. 121 (1997) 432
Oda, K., A. Nakayama, H. Ohara, N. Kitagawa and T. Nomura, Characterization of ion implanted TiN films 121 (1997) 283
Oda, K., see Yokota, K. 121 (1997) 295

Odaka, H., see Haynes, T.E. 121 (1997) 221
Ogasawara, S., see Akizuki, M. 121 (1997) 166
Ogata, K., see Ebe, A. 121 (1997) 207
Ogata, K., see Murakami, Y. 121 (1997) 212
Ogawa, S., see Suzuki, Y. 121 (1997) 107
Ogawa, S., see Okamoto, A. 121 (1997) 179
Ogawa, S., M. Yoshitake, Y. Suzuki, K. Nishigaki, T. Sugioka and H. Toda, The effect of B and P ion implantation on superconducting magnetic shielding in NbTi sheets 121 (1997) 328
Ogi, K., see Itsuki, A. 121 (1997) 116
Ogura, M., N. Yamaji, M. Imai, A. Itoh and N. Imanishi, Trapping of hydrogen in silicon-implanted aluminum 121 (1997) 470
Ohara, H., see Irie, M. 121 (1997) 133
Ohara, H., see Oda, K. 121 (1997) 283
Ohashi, K., see Ohashi, T. 121 (1997) 40
Ohashi, K., see Miyake, K. 121 (1997) 102
Ohashi, T., K. Miyake and K. Ohashi, Molecular dynamics simulations of low energy atomic collisions between an atom and a substrate: Effect of incident angle and energy 121 (1997) 40
Ohdaira, T., see Hirata, K. 121 (1997) 267
Ohno, N., see Current, M.I. 121 (1997) 262
Ohno, N., see Taniguchi, J. 121 (1997) 507
Ohtani, S., M. Inoue and T. Takagi, Nitrogen distribution and microstructure of hot implanted Fe–Ti alloy films . . . 121 (1997) 319
Okada, F., see Tokita, K. 121 (1997) 408
Okamoto, A., see Suzuki, Y. 121 (1997) 107
Okamoto, A., Y. Suzuki, M. Yoshitake, S. Ogawa and N. Nakano, Gold–carbon composite thin films for electrochemical gas sensor prepared by reactive plasma sputtering 121 (1997) 179
Okazaki, K., see Sano, Y. 121 (1997) 432
Ono, H., see Nozaki, S. 121 (1997) 455
Osofsky, M.S., see Horwitz, J.S. 121 (1997) 371
Oyanagi, N., see Gaze, J. 121 (1997) 427
Oyoshi, K., see Hishita, S. 121 (1997) 157
Oyoshi, K., S. Hishita, S. Suehara, T. Aizawa and H. Haneda, Ion beam induced epitaxial crystallization of $SrTiO_3$ . . 121 (1997) 184

Paul, A., see Moro, L. 121 (1997) 151
Petravic, M., see Williams, J.S. 121 (1997) 24
Pindoria, G., F. Wang, M. Badaye and T. Morishita, Observation of long range disorder caused by low energy (20–200 eV) O^+ and Ar^+ beams, in NdBaCuO films 121 (1997) 141
Pond, J.M., see Horwitz, J.S. 121 (1997) 371
Priolo, F., see Rimini, E. 121 (1997) 18

Qadri, S.B., see Horwitz, J.S. 121 (1997) 371
Qin, S., see Husein, I.F. 121 (1997) 226

Rehn, L.E., see Rüders, F. 121 (1997) 30
Rimini, E., A. La Ferla, G. Galvagno, S. Coffa, G. Franzò and F. Priolo, Oxygen-impurity interactions in crystalline silicon: The cases of aluminum and erbium 121 (1997) 18
Rüders, F., L.E. Rehn, P.M. Baldo, E.E. Fullerton and S.D. Bader, Temperature-dependent study of ion-channeling in Fe/Cr superlattices 121 (1997) 30
Ruoff, R.S., see Moro, L. 121 (1997) 151

Sadoh, T., see Baba, A. 121 (1997) 299
Safi, I., see Howson, R.P. 121 (1997) 96
Saito, H., see Nakagawa, S.T. 121 (1997) 36
Saito, K. and Y. Koga, Characterization of carbon films produced by laser ablation of graphite in helium and nitrogen gas atmosphere 121 (1997) 400
Saito, K., see Itadani, T. 121 (1997) 415
Saitoh, K., S. Nakao, H. Niwa, M. Takeda and S. Miyagawa, On the possibility of channeled ion assisted epitaxial growth 121 (1997) 84
Saitoh, K., see Miyagawa, Y. 121 (1997) 340
Saitoh, K., see Shimizu-Iwayama, T. 121 (1997) 450
Sano, Y., N. Mukai, K. Okazaki and M. Obata, Residual stress improvement in metal surface by underwater laser irradiation 121 (1997) 432
Sassa, T., see Nakai, H. 121 (1997) 125

Sato, S., see Nozaki, S. 121 (1997) 455
Satou, M., see Itsuki, A. 121 (1997) 116
Seki, T., T. Kaneko, D. Takeuchi, T. Aoki, J. Matsuo, Z. Insepov and I. Yamada, STM observation of HOPG surfaces irradiated with Ar cluster ions 121 (1997) 498
Setsuhara, Y., see Ebe, A. 121 (1997) 207
Shibata, H., see Katsumata, H. 121 (1997) 146
Shibata, H., see Kobayashi, N. 121 (1997) 199
Shibata, H., see Kotani, M. 121 (1997) 302
Shigesato, Y., see Haynes, T.E. 121 (1997) 221
Shima, T., see Kotani, M. 121 (1997) 302
Shimada, N., see Takeuchi, D. 121 (1997) 345
Shimizu-Iwayama, T., S. Nakao and K. Saitoh, Optical and structural characterization of implanted nanocrystalline semiconductors 121 (1997) 450
Shin, I., see Akizuki, M. 121 (1997) 166
Shindo, T., see Iida, S. 121 (1997) 162
Shinohara, J., see Nakai, H. 121 (1997) 125
Shirai, N., see Tanaka, K. 121 (1997) 404
Short, K.T., see Williams, J.S. 121 (1997) 24
Singh, R.K. and J.M. Fitz-Gerald, Laser induced formation of micro-rough structures 121 (1997) 363
Song, J.H., see Chang, G.S. 121 (1997) 244
Suda, T., see Kakishita, K. 121 (1997) 175
Suda, Y., T. Nakazono, K. Ebihara and K. Baba, Pulsed laser deposition of tungsten carbide thin films on silicon (100) substrate 121 (1997) 396
Suehara, S., see Hishita, S. 121 (1997) 157
Suehara, S., see Oyoshi, K. 121 (1997) 184
Suemasu, T., see Yamada, T. 121 (1997) 378
Suga, T., see Chung, T.R. 121 (1997) 203
Suga, T., see Yang, L. 121 (1997) 519
Sugihara, T. and K. Kuba, Selection of kinetic energy of laser-ablated particles and its application for deposition of Au, Pt and Ag thin films 121 (1997) 392
Sugioka, T., see Ogawa, S. 121 (1997) 328
Sugiyama, I., see Tanaka, K. 121 (1997) 404
Suzuki, R., see Hirata, K. 121 (1997) 267
Suzuki, Y., see Inoue, M. 121 (1997) 1
Suzuki, Y., A. Okamoto, M. Yoshitake and S. Ogawa, Pt thin films prepared by low energy plasma sputtering 121 (1997) 107
Suzuki, Y., see Okamoto, A. 121 (1997) 179
Suzuki, Y., see Kawashita, M. 121 (1997) 323
Suzuki, Y., see Ogawa, S. 121 (1997) 328
Svensson, B.G., see Williams, J.S. 121 (1997) 24
Swain, M.V., see Ikeyama, M. 121 (1997) 335

Tabat, M.D., see Greer, J.A. 121 (1997) 357
Tachiki, M., see Morita, E. 121 (1997) 412
Taga, N., see Haynes, T.E. 121 (1997) 221
Tahara, H., T. Kawabata, L. Zhang, T. Yasui and T. Yoshikawa, Exposure of spacecraft polymers to energetic ions, electrons and ultraviolet light 121 (1997) 446
Takagi, T., see Inoue, M. 121 (1997) 1
Takagi, T., see Ohtani, S. 121 (1997) 319
Takahashi, E., see Ebe, A. 121 (1997) 207
Takano, H., see Yokota, K. 121 (1997) 295
Takaoka, G.H., see Kawashita, M. 121 (1997) 323
Takaoka, G.H., see Tanomura, M. 121 (1997) 480
Takaoka, G.H., T. Hamano, K. Fukushima, J. Matsuo and I. Yamada, Preparation and catalytic activity of nano-scale Au islands supported on TiO_2 . . . . . 121 (1997) 503
Takase, M. and B. Mizuno, An evaluation method for a high concentration profile produced in very low energy doping processes 121 (1997) 288
Takeda, M., see Saitoh, K. 121 (1997) 84
Takeshita, H., see Mitamura, T. 121 (1997) 271
Takeuchi, D., N. Shimada, J. Matsuo and I. Yamada, Shallow junction formation by polyatomic cluster ion implantation 121 (1997) 345
Takeuchi, D., K. Fukushima, J. Matsuo and I. Yamada, Study of Ar cluster ion bombardment of a sapphire surface . . 121 (1997) 493

Takeuchi, D., see Tanomura, M. 121 (1997) 480
Takeuchi, D., see Seki, T. 121 (1997) 498
Takeuchi, T., see Kiuchi, M. 121 (1997) 154
Tanaka, K., N. Shirai, I. Sugiyama and R. Nakata, Pulsed laser deposition of $CdWO_4$ 121 (1997) 404
Tanaka, T., see Ikeyama, M. 121 (1997) 335
Tanaka, Y., see Yamada, T. 121 (1997) 378
Tani, Y., see Kamijo, E. 121 (1997) 110
Taniguchi, J., I. Miyamoto, N. Ohno and S. Honda, Utilizing of hydrocarbon contamination for prevention of the surface charge-up at electron-beam assisted chemical etching of a diamond chip 121 (1997) 507
Tanimura, S., see Fuchigami, H. 121 (1997) 422
Tanomura, M., D. Takeuchi, J. Matsuo, G.H. Takaoka and I. Yamada, Fullerene ion irradiation to silicon 121 (1997) 480
Terasawa, M., see Mitamura, T. 121 (1997) 271
Terasawa, M., see Fan, X. 121 (1997) 331
Terasawa, M., see Yamamoto, A. 121 (1997) 275
Thomé, L., see Nakagawa, S.T. 121 (1997) 36
Thomé, L. and F. Garrido, Formation of metallic nanophases in insulators by high-energy ion-beam mixing 121 (1997) 237
Toda, H., see Ogawa, S. 121 (1997) 328
Tokita, K. and F. Okada, Fabrication of $PbTiO_3$ thin films by laser metalorganic chemical vapor deposition 121 (1997) 408
Toyoda, N., see Matsuo, J. 121 (1997) 459
Toyoda, N., H. Kitani, J. Matsuo and I. Yamada, Reactive sputtering by SF_6 cluster ion beams 121 (1997) 484
Toyoda, N., see Kitani, H. 121 (1997) 489
Tsubakino, H., see Yamamoto, A. 121 (1997) 275
Tsubakino, H., see Fan, X. 121 (1997) 331
Tsubouchi, N., see Enders, B. 121 (1997) 73
Tsui, B.Y., see Chen, L.J. 121 (1997) 231
Tsukamoto, T., see Kobayashi, N. 121 (1997) 199
Tsukamoto, T., see Kotani, M. 121 (1997) 302
Tsunoda, S., see Fuchigami, H. 121 (1997) 422
Tsurushima, T., see Baba, A. 121 (1997) 299

Uchida, H., see Itsuki, A. 121 (1997) 116
Ueda, K., see Fan, X. 121 (1997) 331
Uehara, Y., see Fuchigami, H. 121 (1997) 422
Uekusa, S., see Katsumata, H. 121 (1997) 146
Uekusa, S., see Kobayashi, N. 121 (1997) 199
Ujihira, Y., see Hirata, K. 121 (1997) 267

Wada, T., see Nonogaki, R. 121 (1997) 121
Wang, F., see Pindoria, G. 121 (1997) 141
Whang, C.N., see Kang, H.J. 121 (1997) 53
Whang, C.N., see Choi, S.C. 121 (1997) 170
Whang, C.N., see Chang, G.S. 121 (1997) 244
Whangbo, S.W., see Choi, S.C. 121 (1997) 170
Wielunski, L.S., see Ikeyama, M. 121 (1997) 335
Williams, J.S., K.T. Short, M. Petravic and B.G. Svensson, Oxidation of silicon by low energy oxygen ions 121 (1997) 24
Wilson, M., see Horwitz, J.S. 121 (1997) 371
Woo, J.J., see Chang, G.S. 121 (1997) 244

Yabe, A., see Fuchigami, H. 121 (1997) 422
Yamada, I., see Insepov, Z. 121 (1997) 44
Yamada, I., see Aoki, T. 121 (1997) 49
Yamada, I., see Akizuki, M. 121 (1997) 166
Yamada, I., see Kawashita, M. 121 (1997) 323
Yamada, I., see Takeuchi, D. 121 (1997) 345
Yamada, I., see Matsuo, J. 121 (1997) 459
Yamada, I., see Tanomura, M. 121 (1997) 480
Yamada, I., see Toyoda, N. 121 (1997) 484
Yamada, I., see Kitani, H. 121 (1997) 489
Yamada, I., see Takeuchi, D. 121 (1997) 493
Yamada, I., see Seki, T. 121 (1997) 498
Yamada, I., see Takaoka, G.H. 121 (1997) 503

Yamada, S., see Nonogaki, R. 121 (1997) 121
Yamada, T., Y. Tanaka, T. Suemasu and Y. Kohtoku, Synthesis and characterization of SiC–Si_3N_4 composites by dual irradiation of CO_2 and excimer lasers 121 (1997) 378
Yamaji, N., see Ogura, M. 121 (1997) 470
Yamamoto, A., H. Tsubakino, M. Ando, M. Terasawa and T. Mitamura, Effects of ion-implantation with nitrogen ion on microstructures in deformed iron 121 (1997) 275
Yamamoto, A., see Fan, X. 121 (1997) 331
Yamamoto, M., see Kiuchi, M. 121 (1997) 154
Yamamoto, S., see Mitamura, T. 121 (1997) 271
Yamamoto, Y., see Nakata, J. 121 (1997) 306
Yamamuro, K., see Morita, E. 121 (1997) 412
Yamazaki, H., see Nakata, J. 121 (1997) 306
Yang, J.J. and L.J. Chen, High resolution transmission electron microscope study of solid phase epitaxial growth of very high dose, low energy P^+ implanted (001)Si 121 (1997) 195
Yang, J.J. and L.J. Chen, Characterization and removal of residual defects in high dose, very low energy BF_2^+-implanted (001)Si 121 (1997) 291
Yang, L., see Chung, T.R. 121 (1997) 203
Yang, L., N. Hosoda and T. Suga, TEM investigation of the stainless steel/aluminum interface created by the surface activated bonding method 121 (1997) 519
Yasui, I., see Haynes, T.E. 121 (1997) 221
Yasui, T., see Tahara, H. 121 (1997) 446
Yasuoka, A., see Murakami, T. 121 (1997) 257
Yip, S., see Bulatov, V. 121 (1997) 251
Yokota, K., K. Hosokawa, K. Oda, F. Miyashita, K. Hirai, H. Takano, M. Kumagai, Y. Ando and K. Matsuda, Reliability of shallow n^+-type layers formed in dual As and B implanted silicon by rapid thermal annealing 121 (1997) 295
Yoneda, T., see Kajiyama, K. 121 (1997) 315
Yoon, Y.H., see Lee, J.W. 121 (1997) 474
Yoshikawa, T., see Tahara, H. 121 (1997) 446
Yoshitake, M., see Suzuki, Y. 121 (1997) 107
Yoshitake, M., see Okamoto, A. 121 (1997) 179
Yoshitake, M., see Ogawa, S. 121 (1997) 328
Yu, I.G., see Cho, H.J. 121 (1997) 137

Zhang, J.Y., see Boyd, I.W. 121 (1997) 349
Zhang, L., see Tahara, H. 121 (1997) 446
Zhao, X., see Hirata, K. 121 (1997) 267
Zhou, W., see Gaze, J. 121 (1997) 427
Zhou, Y.-Z., see Husein, I.F. 121 (1997) 226
Zhu, D.H., see Kobayashi, N. 121 (1997) 199